

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 231752US26YA		SERIAL NO. 10/673,467	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Eric J STRANG			
				FILING DATE September 30, 2003		GROUP 2128	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	US 6,571,371	5/2003	Coss, et al.			
	AB	US 6,763,277	7/2004	Allen, et al.			
	AC	US 6,529,789	3/2003	Campbell, et al.			
	AD	US 6,628,809	9/2003	Rowe, et al.			
	AE	US 6,728,591	4/2004	Hussey, et al.			
	AF	US 6,774,998	8/2004	Wright, et al.			
	AG	US 2005/0016947	1/2005	Fatke, et al.			
	AH	US 2005/0010319	1/2005	Patel, et al.			
	AI	US 2003/0078738	4/2003	Wouters, et al.			
	AJ	US 2004/0078319	4/2004	Madhavan, et al.			
	AK	US 5,866,437	2/1999	Chen, et al.			
	AL	US 2004/0044513	3/2004	Kitahara, Noriaki			
	AM	US 2004/0102934	5/2004	Chang, Fang-Cheng			
	AN	US 2003/0135302	7/2003	Hung, et al.			
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION		
					YES	NO	
	AO	CN 1335558A	2/13/2002	China (with Partial English Translation)	X		
	AP	WO 02/07210 A2	1/24/2002	WIPO		X	
	AQ	EP 0 718 595 A2	6/26/1996	EUROPE		X	
	AR	JP 2004-527117	9/2/2004	Japan		X	
	AS	WO 03/060779 A1	7/24/2003	WIPO		X	
	AT	JP 2005-515623	5/26/2005	JAPAN (With English Abstract)		X	
	AU	WO 03/009345 A2	1/30/2003	WIPO		X	
	AV	JP 2005-522018	7/21/2005	JAPAN (With English Abstract)		X	
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW	Robert W. ATHERTON, et al., "Detailed Simulation for Semiconductor Manufacturing", Proceedings of the 1990 Winter Simulation Conference					
	AX	Angus J. MACDONALD, et al., "Integrated CAM and Process Simulation to Enhance On-Line Analysis and Control of IC Fabrication"; IEEE Transactions on Semiconductor Mfg., Vol. 3, No. 2, May 1990					
	AY	Paul P. CASTRUCCI; "Emerging Paradigms in Semiconductor Manufacturing"; 1990 Int'l Semiconductor Mfg., Science Symposium; IEEE 1990					
	AZ	Yea-Huey SU, et al. "Conceptual Framework for Manufacturing Service Provisioning by Virtual Fabs"; 1998 NSC Republic Of China; 1998 Semiconductor Mfg. Technology Workshop				<input type="checkbox"/> Additional References sheet(s) attached	
Examiner					Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
	AAA	US 6,615,097	9/2003	Ozaki, Hiroji			
	AAB	US 6,905,895	6/2005	Coss, et al.			
	AAC	US 6,757, 645	6/2004	Chang, et al.			
	AAD	US 6,643,616	11/2003	Granik, et al.			
	AAE	US 6,618,856	9/2003	Coburn, et al.			
	AAF	US 2004/0044513	3/2004	Kitahara, Noriaki			
	AAG	US 2005-0071037	3/31/2005	Strang			
	AAH	US 2005-0071035	3/31/2005	Strang			
	AAI	US 2005-0071038	3/31/2005	Strang			
	AAJ	US 2005-0071036	3/31/2005	Mitrovic			
	AAK	US 2005-0071039	3/31/2005	Mitrovic			
	AAL	US 6,198,980 B1	3/2001	Costanza, John R.			
	AAM						
	AAN						
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		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AAO	JP 2003-17471	1/17/2003	JAPAN (With English Abstract)			X
	AAP	WO 02/065511 A2	8/22/2002	WIPO			X
	AAQ	JP 2004-524685	8/12/2004	JAPAN			X
	AAR	WO 02/069063 A2	9/6/2002	WIPO			X
	AAS	JP 2004-531878	10/14/2004	JAPAN			X
	AAT	JP 2000-517473	12/26/2000	JAPAN (With English Abstract)			X
	AAU	WO 03/058699 A1	7/17/2003	WIPO			X
	AAV	JP 2005-514790	5/19/2005	JAPAN (With English Abstract)			X
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AAW	Chanettre RASMIDATTA, et al. "New approaches for Simulation of Wafer fabrication : The Use of Control Variates and Calibration Metrics" Proceedings of 2002 Winter Simulation Conference; 2002					
	AAX						
	AAZ						
					<input type="checkbox"/> Additional References sheet(s) attached		
Examiner					Date Considered		

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EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AAAA	US 7,107,571 B2	9/2006	Chang, et al.		
	AAAB	US 5,741,070	4/21/1998	Mehrdad Mahmud Moslehi		
	AAAC	US 2004/0058255 A1	3/25/2004	Scott Jessen, et al		
	AAAD	US 5,539,652	7/23/1996	Tegethoff		
	AAAE	US 6,581,029 B1	6/17/2003	Fisher		
	AAAF	US 2003/0003607	1/2/2003	Kagoshima et al		
	AAAG	US 6,185,472	2/6/2001	Onga, et al.		
	AAAH	US 7,047,095 B2	5/16/2006	Tomoyasu		
	AAAI	US 6,587,744 B1	7/1/2003	Stoddard, et al.		
	AAAJ					
	AAAK					
	AAAL					
	AAAM					
	AAAN					
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		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO	
	AAAO	JP 2002-367875	12/20/2002	JAPAN		X
	AAAP	JP 2003-502771	1/21/2003	JAPAN		X
	AAAQ	WO 02/077589 A2	10/3/2002	WIPO		X
	AAAR					X
	AAAS					X
	AAAT					X
	AAAU					X
	AAAV					X
	AAAW					X
	AAAX					X
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)						
	AAAY	Su-shing CHEN, "AEMPES: An expert system for in-situ diagnostics and process monitoring"; Semiconductor Manufacturing Science Symposium, 1990., IEEE/SEMI International, 21-23 May 1990 Pages 119-122				
	AAAZ	Heru SETYAWAN, et al. "Visualization and numerical simulation of fine particle transport in a low-pressure parallel plate chemical vapor deposition reactor", Chemical Engineering Science 57 (2002) pages 497-506				
					<input type="checkbox"/> Additional References sheet(s) attached	
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